



Patent Application No. 10/712,196  
Docket No. JSF02-0004

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

5 Applicant(s): Chang-Feng Wan ) Art Unit: 2811  
Serial No.: 10/712,196~~6~~ )  
10 Filed: 05/09/2002 ) Examiner: Shouxiang Hu  
For: **SYSTEM AND METHOD OF FABRICATING MICRO CAVITIES**

Director of the US Patent and Trademark Office  
PO Box 1450  
Alexandria, VA 22313-1450

I hereby certify that this correspondence is being deposited with the  
United States Postal Service as Express Mail, Express Mail No.  
ER 269412810 addressed to:  
-uS

Director of the US Patent and Trademark Office  
PO Box 1450  
Alexandria, VA 22313-1450

on 9/15/2005

Signature

15

**AMENDMENT**

In response to the Office Action dated 05 May 2005, in  
response to communication filed on 25 February 2005. Please  
5 amend the above-identified patent application as follows:

**In the figures**

Please find attached figures for insertion.  
10

**In the claims**

Please withdraw claims 22-27 from consideration as  
claims pursuant to Examiner's restriction requirement.  
15

Please amend the claims as follows:

1. (Currently amended)

A method of manufacturing a plurality of micro  
20 enclosures on a substrate wafer, comprising steps of:

(1) bonding a cap wafer to said substrate wafer with  
an adhesive layer;

~~(2) thinning said cap wafer to desired thickness;~~